

## **AMENDMENTS TO THE CLAIMS**

**Claim 1 (Original)** A substrate transport apparatus comprising:

a substrate transport pod that can be sealed hermetically for holding substrates therein,  
which are taken out from a processing apparatus;

at least one of a particle filter, a chemical filter, and a dehumidifying apparatus for  
removing, respectively, particulate substances, chemical substances, and moisture from a gas  
circulated inside the pod;

a gas circulation apparatus for circulating a purified gas or purge means;

a holding apparatus for holding the substrates;

data storing means; and

a power supply for driving the dehumidifying apparatus and/or the circulation apparatus  
and the data storing means.

**Claim 2 (Original)** A substrate transport apparatus according to claim 1, wherein said data  
storing means is provided for controlling an operation of the dehumidifying apparatus and/or the  
circulation apparatus.

**Claim 3 (Original)** An apparatus according to claim 1, further comprising:

an identifier ID for distinguishing individual pods; and

means for sending and receiving control information with outside data storing means.

**Claim 4 (Original)** A substrate transport apparatus according to claim 1, wherein the pod has  
means for receiving external signals, and controls internal environment in the pod according to the  
external signals.

**Claim 5 (Original)** A substrate transport apparatus according to claim 1, wherein an internal  
environment of the pod is controlled by sending and receiving information between the pod and a  
processing apparatus.

**Claim 6 (Original)** A substrate transport apparatus according to claim 1, wherein the pod is provided with processing history management information on substrates in said data storing means.

**Claim 7 (Original)** A substrate transport apparatus according to claim 6, wherein the processing history management information is transferred from one pod to other pod.

**Claim 8 (Original)** A substrate transport apparatus according to claim 6, wherein the processing history management information is communicated by way of a host computer network.

**Claim 9 (Original)** A substrate transport apparatus according to claim 6, wherein the processing history management information is transferred from one pod to other pod by a controller provided on a processing apparatus.

**Claim 10 (Original)** A substrate transport apparatus according to claim 6, wherein the processing history management information is transferred from a pod used in a preceding step to a pod to be used in a succeeding step.

**Claim 11 (Original)** A substrate transport apparatus according to claim 1, wherein an information on a pod to be washed is stored in the data storing means.

**Claim 12 (Original)** A substrate transport apparatus according to claim 11, wherein said information is sent to a pod washing machine so that the pod can be selected and subjected to washing.

**Claim 13 (Original)** A substrate transport apparatus according to claim 1, wherein a change of information stored in said data storing means is conducted by communication with outside data storing means by signal input/output portion.

**Claim 14 (Original)** A substrate transport apparatus according to claim 6, wherein a change of the processing history management information is conducted by signal input/output portion by sending and receiving information with outside data storing means.

**Claim 15 (Original)** A substrate transport apparatus according to claim 6, wherein a change of lot processing history management information is conducted by signal input/output portion by sending and receiving information with outside data storing means.

**Claim 16 (Original)** A substrate transport apparatus according to claim 1, wherein a washing interval information of the pod is stored in said data storing means.

**Claim 17 (Original)** A substrate transport apparatus according to claim 1, wherein a filter change interval information, or an information of a secondary battery is stored in said data storing means.

**Claim 18 (Original)** A substrate transport apparatus according to claim 17, wherein the filter change interval information of a pod is managed from a product of a processed gas volume and an operation time of the circulation apparatus or the dehumidifying apparatus.

**Claim 19 (Original)** A substrate transport apparatus according to claim 16, wherein the washing interval information is estimated from an operation time of the gas circulation apparatus.

**Claim 20 (Original)** A substrate transport apparatus according to claim 1, wherein residual power of a secondary battery provided for the pod is measured, and charged to a necessary level of power.

**Claim 21 (Original)** A substrate transport apparatus according to claim 6, wherein the processing management history information on individual pod is communicated by wire or radio transmission through a network.

**Claim 22 (Original)** A substrate transport apparatus according to claim 2, wherein an information on the pod to be washed is sent to a pod washing machine so that the pod can be selected and subjected to washing.

**Claim 23 (Original)** A substrate transport pod for containing, storing or transporting substrates, comprising:

- a pod main body and a door for hermetic sealing of the pod main body, which is formed primarily of a material having moisture absorption coefficient of not more than 0.1%, wherein the pod main body is in contact with the substrates directly or indirectly and has a conductive part so as to enable static charges to be drained from the pod main body; and

- a sensor provided for detecting whether the door is opened or closed;

- wherein a gas circulation apparatus and/or a dehumidifying apparatus is installed in said pod main body, and is controlled to operate by detecting that the door is closed or opened.

**Claim 24 (Original)** A substrate transport pod for containing, storing or transporting substrates, comprising:

- a pod main body and a door for hermetic sealing of the pod main body, which is formed primarily of a material having moisture absorption coefficient of not more than 0.1%, wherein the pod main body is in contact with the substrates directly or indirectly and has a conductive part so as to enable static charges to be drained from the pod main body; and

- a sensor provided for detecting presence of the substrates;

- wherein a gas circulation apparatus and/or dehumidifying apparatus is controlled to operate in accordance with detection signal of the sensor for detecting the presence of the substrates.

**Claim 25 (New)** A method for manufacturing a semiconductor device by transporting substrates between a plurality of processes, comprising:  
coating a phot-resist on a semiconductor substrate;  
loading the semiconductor substrate into a pod; and  
prioritizing a reduction of base substances in said pod so as to suppress a T-top formation.

**Claim 26 (New)** The method of claim 25, wherein said pod is used for transporting the semiconductor substrates between manufacturing processes in a floor, between floors inside a plant, and between plants, or for storing the semiconductor substrates.

**Claim 27 (New)** The method of claim 25, wherein said pod is used for transporting the semiconductor substrates between a resist coating process, an exposure process, and a development process.

**Claim 28 (New)** A substrate transport pod for containing, storing or transporting substrates, comprising:

a pod main body for loading the substrates therein;  
a door for hermetic sealing of the pod main body; and  
control means for prioritizing reduction of base substances in said pod;  
wherein said pod is used in an apparatus in which resist coating, exposure, and development are not continuously performed at an interface section thereof.

**Claim 29 (New)** The pod of claim 28, wherein a level of ammonia inside said pod is less than  $1\mu\text{g}/\text{m}^3$ .